

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Docket No. : CIL-10972

Serial No.: 10/086,614 Art Unit: 1762

Filed: March 1, 2002 Examiner: W. Markham

For : Ion-Assisted Deposition Techniques For

The Planarization Of Topological Defects

PETITION FOR EXTENSION OF TIME UNDER 37 CFR 1.136(a)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Applicant: Paul B. Mirkarimi et al.

Dear Sir:

This is a request under the provisions of 37 CFR 1.136(a) to extend the period for filing a reply in the above identified application.

The requested extension fee for a three month extension (37 CFR 1.17(a)(3) is \$1020.

The Commissioner is hereby authorized to charge this fee (\$1020) to Deposit Account Number 501913.

If any impediments remain, please contact the undersigned at 808-875-0012.

Respectfully submitted,

08/23/2005 HMARZI1 00000019 501913 10086614

Dated: August 15, 2005

01 FC:1253 1020.00 DA

John P. Wooldridge

Attorney for Applicant

Registration No. 38,725